

- Polysilicon: 490
- Wafer size: 6 inch
- Upgraded TFT monitors
- Wafer detection
- Incl maintenance console
- No chiller and no pump, but with ENI RF Generator)

LAM 490 AutoEtcher

- Single-wafer processing
- Fully automated microprocessor control
- Cassette-to-cassette wafer processing
- Vacuum load locked
- Programmable, variable electrode spacing
- Endpoint detection
- Configurable for 3-inch to 6-inch wafers
- Stand-alone or bulk-head mount configuration